

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the Application of:

Philipp Steinmann et al.

Examiner: TBD

Serial No: TBD

Art Unit: TBD

Filed: 05/10/01

Docket No.: TI-29881

For: METHOD OF INTEGRATING A THIN FILM RESISTOR IN A MULTI-
LEVEL METAL TUNGSTEN-PLUG INTERCONNECT

PRELIMINARY AMENDMENT

May 10, 2001

Assistant Commissioner for Patents

Washington, DC 20231

Dear Sir:

Please amend the above referenced application as follows:

In the Specification:

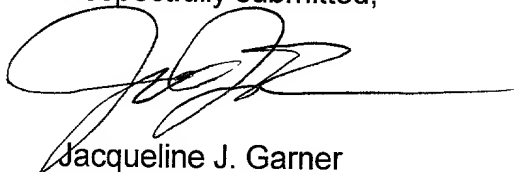
Page 1, before line 1, insert --This application claims priority under 35 USC §
119(e)(1) of provisional application numbers **60/208,705** filed **06/01/00**.--

REMARKS

Entry of the foregoing amendment prior to examination is respectfully requested.

If the Examiner has any questions or other correspondence regarding this application, Applicant requests that the Examiner contact Applicant's attorney at the below listed telephone number and address.

Respectfully submitted,



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FOOTNOTES